

ABSTRACT

A micromechanical latching system usable to achieve small element stabilization during and following the fabrication of a MEMS device. Realization of sliding latching elements from semiconductor materials such as polysilicon using integrated circuit techniques is included. Provisions for manual manipulation of the latching elements between unlatched and latched conditions are also included along with two exemplary MEMS device applications of the latching system. The achieved latching system contributes to substrate interference free improved flip-chip fabrication of Integrated Microsystem micromechanical devices by way enabling improved alignment accuracy processing.